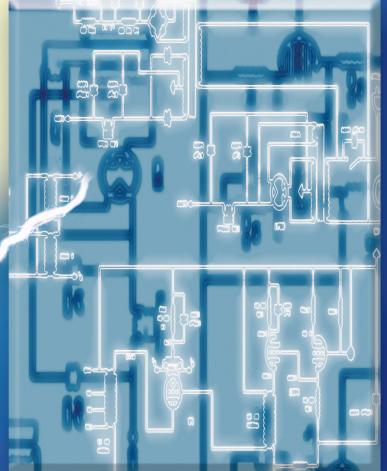
# ESD Avoiding Circuits for Solving OTP Memory Falsely Programmed Issues

# **Abstract**

One-time program (OTP) memories are programmed for memory design without electrostatic discharge (ESD) stresses. However, in reality, ESD events are not selective and thus ESD currents can falsely program OTP memory cells. Many integrated circuit (IC) designers focus only on improving OTP memory control architectures to avoid memory being falsely programmed without mentioning the ESD-introduced memory errors. This article investigates a new ESD architecture and novel ESD avoiding circuits, aiming to solve ESD-introduced memory falsely programmed issues. It should be noted that this article focuses on ESD circuit designs to protect OTP memory instead of OTP control architectures. With such new ESD schemes, our prototype circuits have demonstrated that memory cells can indeed be programmed at IC program mode without ESD stresses.

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# Embedded non-volatile memory devices can provide capabilities for system program code storage, configuration setting, and product identification setting.

#### I. Introduction

mbedded non-volatile memory devices can provide capabilities for system program code storage, configuration setting, and product identification setting [1–4]. However, the complexity of device fabrication may lead to low product yield and high process cost. In this article, a new embedded one time programmed bitcell (Neobit) [5] device, fabricated by mature process technologies with minor changes, is used as the memory cell. It is noted that such non-volatile OTP memories should be programmed under IC program mode, but should not be programmed under IC read and other IC operation modes. ESD events can induce non-volatile memories falsely programmed under IC transportations and other unpredicted stresses. This article focuses on the issue of how to avoid ESD falsely programming of non-volatile memories.

In this study, Neobit is said to be programmed if Neobit has current equal to or larger than 1  $\mu$ A. If Neobit is not operated under program processes, but the memory cell is programmed on unpredicted occasions, the status is referred to as the memory falsely programmed issue.

ESD device turn-on voltage (Vt1) must be designed to be larger than the programming voltage ( $V_{prog}$ ), so that ESD protection devices can keep the off state during IC program operations. On the contrary, Vt1 must be designed as small as possible, so that ESD device can turn on effectively to protect Neobit. Although the Neobit programmed time ( $100~\mu s$ ) is much larger than the ESD event time ( $100~\mu s$ ) is much larger than the ESD event time ( $100~\mu s$ ) arge Vt1 can still result in memory falsely programmed under ESD stresses. This is because ESD currents possibly enter Neobit if ESD device does not turn on to dissipate ESD charges. In this article, ESD avoiding circuit [6], which uses one inverter for controlling transmission N/PMOS transistors, is designed for preventing ESD currents from entering OTP cells.

This IC test-chip is processed by  $0.25~\mu m$  silicon technology and there are four kinds of Voltage Program PAD (VPP) circuits under the framework of this article. The first VPP circuit, Circuit A, is Gate-Grounded NMOS transistor (GGNMOST); the second, Circuit B, is Gate-Driven NMOS transistors (GDNMOST); the third, Circuit C, uses a GGNMOST as ESD protection circuit and an ESD avoiding circuit as ESD current stopping wall between

VPP and OTP memory cells; the last, Circuit D, consists of GDNMOST and ESD avoiding circuit.

Firstly, Circuit A cannot bypass ESD currents effectively and cannot prevent ESD currents from entering OTP cells, consequently OTP cells will encounter falsely memory programmed issues. Secondly, Circuit B can obtain a much lower Vt1, but memory falsely programmed issue still exists because ESD currents are not selective to flow only into ESD NMOS transistors. Thirdly, Circuit C still has memory falsely programmed issue, where although ESD avoiding circuit is designed for preventing ESD currents from entering OTP cells, GGNMOST cannot effectively dissipate ESD currents. Finally, Circuit D has no memory falsely programmed issue because GDNMOST can turn on effectively under ESD stresses and ESD avoiding circuit can prevent ESD currents from entering OTP cells.

To carry out the study below, in Section II memory architecture description is firstly described. ESD circuits are then discussed in Section III and ESD testing experiments are listed in Section IV. Finally, to analyze and demonstrate the results, falsely programming analysis and simulation analysis are presented in Section V and Section VI, respectively.

# II. Memory Architecture Description

Metal fuse is often used as one switch, as illustrated in Fig. 1(a). Under IC normal operation conditions, terminal A connects to terminal B. Once large currents flow through the metal to burn it out, terminal A disconnects to terminal B and there is an opening with a very high resistor between the two terminals. However, the

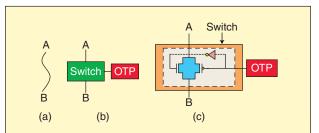


Figure 1. Traditional metal fuse and OTP memory applications. (a) shows the traditional metal fuse, (b) shows switch controlled under OTP memory, and (c) shows one transmission gate structure and one inverter as the switch connected with OTP memories.

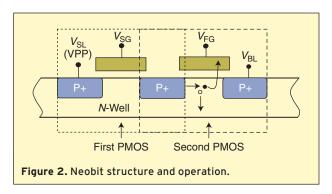
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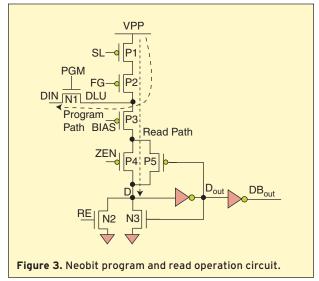
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opening gives an entrance for contaminants, such as water vapor, which destroy surrounding devices, and as a result this lowers the reliability of the surrounding devices. Metal cut is a relatively more time-consuming procedure since enough heats are necessary to cut the metal. Furthermore, metal fuse cannot be connected under electrical operations after the metal is cut.

Due to the above three major disadvantages of metal fuse, easy contaminant entrance, time-consuming metal cut and non-recovered characteristics under electrical operations, one-time program memory (OTP) is applied to replace metal fuse here. Fig. 1(b) illustrates OTP memory which controls the switch. If OTP memory provides a low-level voltage before it is programmed and provides a high-level voltage after it is programmed, OTP memory can connect terminal A and terminal B together before OTP memory is programmed, whereas OTP memory can disconnect terminal A and terminal B after OTP memory is programmed. The detailed structure of OTP memory, which controls the switch, is shown in Fig. 1(c). Herein, terminals A and B become the switch composing of transmission N/PMOS transistors and one inverter.

Fig. 2 illustrates the Neobit architecture [7] that forms the OTP memory cell in this study. It contains two PMOS



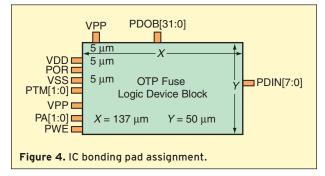


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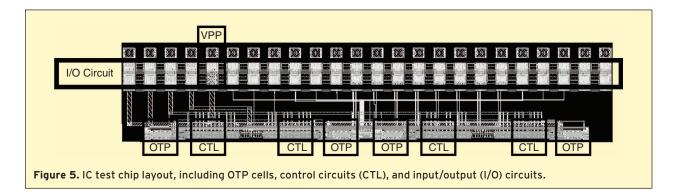
transistors. The 1st PMOS transistor operates as one switch and the 2nd PMOS transistor is the programmed cell. When performing the program operations, wordline voltage V<sub>SG</sub> is applied on the selected poly gate of the 1st PMOS transistor, thereby turning on a P-channel. A source-line voltage V<sub>SL</sub> is applied on the P+ source region of 1st PMOS transistor and is connected to the programming bonding VPP. A well voltage V<sub>NW</sub> is applied on the N-well. A bit-line voltage VBL is applied on the P+ drain region of the 2nd PMOS transistor. The floating gate of the 2nd PMOS transistor is in a floating state. Under the above voltage conditions, a coupling voltage is sensed by the floating gate due to capacitive coupling effect, thereby turning on a P-channel under the floating gate. Hot carriers such as electrons, which are accelerated by the electric field at the depletion region, tunnel through the floating poly gate oxide layer by way of the turned on P-channel, and are finally trapped inside the P+ floating poly gate.

Fig. 3 indicates OTP cell operations [8]. On the one hand, PMOS transistor P1 and NMOS transistor N1 turn on at the IC program mode. VPP is connected to 7 V so that PMOS transistor P2 can be programmed. If the OTP cell is not designed for being programmed, both transistors P1 and N1 will turn off. On the other hand, P1 turns on but N1 turns off at the IC read mode. Both PMOS transistors P3 and P4 turn on and VPP is tied to 3.3 V. If P2 is programmed, then terminal D can own a high-level voltage so that terminal Dout can obtain a low-level voltage. Then, data output terminal DBout obtains a high-level voltage if P2 is not programmed.

Briefly summarizing, OTP memory can provide a high-level voltage if Neobit is programmed and OTP memory can provide a low-level voltage if Neobit is not programmed. Through selecting Neobit to be programmed or non-programmed, IC designers can obtain switch-off or switch-on functions. Since Neobit operates under electrons, absorbed in floating poly gate oxide for being programmed, the electrons permanently exist in the floating poly gate oxide after the cell is programmed, except that the cell is exposed in the complicated cell



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recovery procedures. In other words, electrons cannot be changed even the power supply turns off, so switch-off and switch-on characteristics such as the metal fuse characteristics cannot be easily changed.

There exist not only Neobit but also many other kinds of bonding pads for providing IC suitable operation voltages in OTP memories, as shown in Fig. 4. VDD provides IC power supply and VSS provides IC grounding signals. POR gives power-on reset function and PTM is for test mode enabling. VPP is a 7 V pad in program cycle and a 3.3 V pad in read cycle. PA is the address input for program control and PWE defines program cycle. PDIN is designed for data input and PDOB is designed for data output [9]. Fig. 5 and Fig. 6 illustrate test-chip layout and microphotograph, respectively. The IC test-chip circuits can be classified into three major parts, OTP memory control circuit (CTL), OTP memory cells and I/O circuits.

According to Neobit operations and other control signals, circuit designers can obtain switch-on or switch-off characteristics from OTP memory. OTP memory not only owns the same switch functions as metal fuse, but also overcomes metal fuse's three disadvantages. Firstly, OTP memory has no contaminant issue because there is no metal opening. Secondly, all the OTP memory programmed operation procedures are finished under electrical controls, so much time is saved in OTP memory. Finally, OTP memory users can use UV photo to delete floating PMOS transistor poly gates' electrons, so they can recover IC to the pre-programmed status under electrical operations.

Unlike other types of Flash memories, Neobit structure is not suitable for multiple-time being programmed and erased, because UV photo consumes much time for

memory erasure and charges are stored in the poly gate oxide. Neobit is designed for being programmed and erased in the applications with recycling frequencies less than 10, although they can be used in more cycles. This is the so-called One-Time Program (OTP) memory.

#### **III. ESD Circuit Discussion**

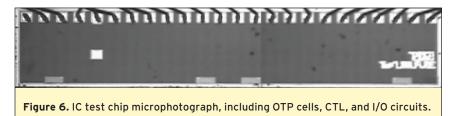
In order to protect IC against ESD damage while not to let ESD circuit interfere IC normal operations, Gate-Grounded NMOS transistors are often used as ESD circuit, such as Circuit A discussed above. To reduce ESD device turn-on voltage, power-up reset circuit [10] is used to locate the poly gate of ESD NMOS transistor for forming Gate-Driven circuit, as illustrated in Circuit B. Although there are ESD protection circuits, ESD currents can enter OTP memories from VPP, so ESD avoiding circuit is proposed to stop ESD currents. Circuit C combines Circuit A and ESD avoiding circuit. Circuit D combines Circuit B and ESD avoiding circuit. Circuits A-D will be described below in more details.

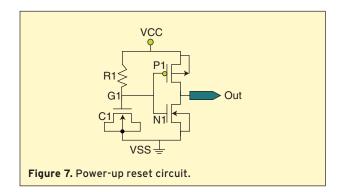
For negative ESD charges, they can be easily dissipated by the parasitic diode D1 of Circuits A-D, therefore the descriptions given below will focus on positive ESD charges only. Moreover, from IC area consumption points of view, GGNMOST is much saved as compared to GDNMOST, because ESD-driven circuits cost a lot of layout area. Normally, the gate-driven circuit layout size is almost equal to ESD NMOS transistor size. This is the other reason why GGNMOST is the typical ESD protection circuit. However, such simple ESD protection circuit cannot protect OTP memory cells from ESD damages, so we need to discover the new ESD circuit.

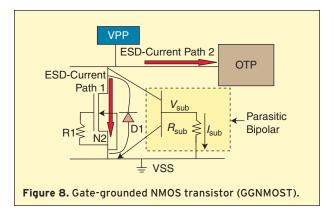
# Circuit A: Gate-Grounded NMOS Transistor (GGNMOST)

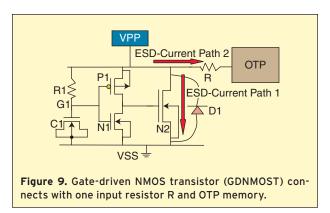
GGNMOST is often used as ESD protection device, as illustrated in Fig. 8. There are NMOS transistor N2 as ESD device and one gate-coupled resistor R1 between transistor N2 poly gate and grounding terminal VSS.

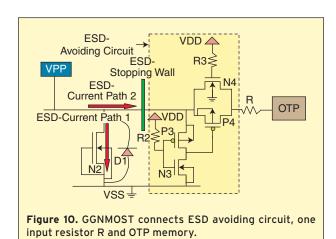
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Under IC normal operations, there are no leakage currents because transistor N2 poly gate is connected to VSS through R1. The parasitic NPN bipolar of transistor N2 can turn on to dissipate ESD currents under positive ESD stresses [11]. When positive ESD events occur, Isub can go through Rsub to make base-emitter voltage VBE larger than 0.7 V and then turn on the parasitic bipolar.

# Circuit B: Gate-Driven NMOS Transistor (GDNMOST)

A typical power-up reset circuit in the prior art is shown in Fig. 7. During VCC starting-up period, terminal G1 keeps in a low-level voltage due to ground terminal VSS coupling through capacitor C1. Then, transistor P1 can turn on to trigger the output terminal OUT for having a high-level voltage. After a time constant that is decided by the product of resistor R1 and capacitor C1, terminal G1 voltage increases to a high-level voltage to turn on N1 and then pull terminal OUT to a low-level voltage state. If terminal OUT is connected to the poly gate of ESD NMOS transistor, as illustrated in Fig. 9, the power-up reset circuit can turn on ESD NMOS transistor once ESD events occur and turn off ESD NMOS transistor under IC normal operations. The power-up reset circuit on ESD NMOS poly gate connected with ESD NMOS transistor is called Gate-Driven NMOS transistor (GDNMOST).

In order to reduce ESD architectures' turn-on voltages (Vt1), GDNMOST is often used as ESD protection circuit. ESD operation mechanisms are as follows. Because ESD event period is about  $0.25~\mu s$  [12], the product of R1 value and C1 value (R1C1 time constant) is designed as  $1~\mu s$ . Considering ESD testing item "VPP-VSS", which indicates that VPP is under ESD stresses, terminal VSS is grounded and other bonding pads are floating. Capacitor C1 couples VSS ground voltage to terminal G1 because R1C1 time constant is larger than ESD period. This capacitor coupling can keep terminal G1 in a low-level voltage to turn on transistor P1, thereby turning on transistor N2 so Vt1 of GDNMOST is much smaller than Vt1 of GGNMOST.

# Circuit C: GGNMOST + ESD Avoiding Circuit

Compared with Circuit A, ESD avoiding circuit is inserted between VPP and OTP cells, as shown in Fig. 10. There are two major circuit design architectures in ESD avoiding circuit. One is the inverter circuit and the other is transmission N/PMOS circuit. The inverter circuit is composed of transistors P3 and N3 for controlling the gate terminal of PMOS transistor P4. The common gate terminal of P3 and N3 is connected to the power terminal VDD through resistor R2. The gate terminal of NMOS transistor N4 is connected to power terminal VDD through resistor R3. The purpose of transistor P4 is for preventing

ESD currents from entering OTP cells. N-well of transistor P4 must be connected to VPP, so that the programming voltage can be transmitted to OTP cells at IC programming mode. Transistor N4 is the auxiliary device for transmitting high programming voltage to OTP cells.

IC operations of ESD avoiding circuits are described as follows. On the one hand, under IC normal operations (VPP=VDD), VDD can turn on transistor N3 and turn off transistor P3. This makes the gate terminal of transistor P4 have a low-level voltage so that it can turn on. VDD can also turn on transistor N4 through resistor R3. Transistors P4 and N4 can execute VPP signal pass function under IC normal operations. On the other hand, at IC programming mode (VDD=3.3 D and VPP=7 V), both transistors P3 and N3 can turn on. Transistor P3 size is designed to be much smaller than transistor N3 size, so transistor P4 gate voltage is at a low-level voltage as compared to transistor P4 n-well voltage. In this study, transistor P3 channel width is designed as  $2 \mu m$  and transistor N3 channel width  $40 \mu m$ . Hence, 7 V can be transmitted from VPP to OTP cell. Turning on transistors P3 and N3 can result in 0.5 mA current flowing from VPP to ground VSS. However, the programming mode is not IC normal operation mode and OTP memory consumes 4 mA at programming mode. Furthermore, OTP memory program depends on VPP voltage that is not impacted by this extra leakage current and 0.5 mA is a small value compared with 4 mA programming current, therefore the leakage current drawback of ESD avoiding circuit can be overcome by IC programming applications.

Consider ESD testing item "VPP-VSS" again. This kind of ESD testing condition is ESD charges entering VPP, terminal VSS tied to 0 V, and all other bonding pads floating controlled by ESD testing machine program definitions. On the one hand, same as Circuits A and B, positive ESD charges must be dissipated through the

parasitic bipolar of transistor N2. On the other hand, ESD avoiding circuit can act as one ESD current stop wall. Terminal VDD is charged to a low-level voltage because terminal VDD is floating at ESD events and thus transistor P3 can turn on. Positive ESD charges can be coupled to the gate terminal of transistor P4 to turn it off through transistor P3. Meanwhile, transistor N4 can also turn off. Consequently, both transistors P4 and N4 turn off for forming one ESD current stop wall. Typically, each transistor P3, P4 and N4 can turn on or off in 0.2 ns.

# Circuit D: GDNMOST + ESD Avoiding Circuit

Compared with Circuit C, GDNMOST is utilized as ESD protection circuit to replace

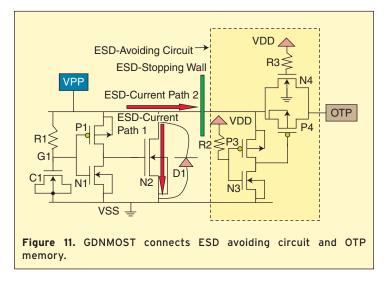
GGNMOST, as illustrated by Fig. 11. GDNMOST can obtain a smaller Vt1 in ESD devices and ESD avoiding circuit can form an ESD current avoiding wall in the OTP memory program path.

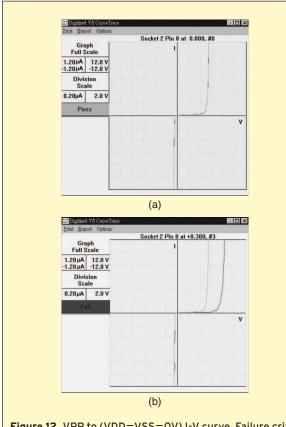
#### IV. ESD Testing Experiments

ESD testing experiments are designed for "VPP-other IC bonding pads" because falsely programming resources come from VPP. Testing combinations are divided into three groups, "VPP-VDD", "VPP-VSS", and "VPP-IO". Herein, VDD is the power supply that provides IC power sources. VSS provides a ground voltage for IC. IO represents input and/or output signal pads, which can provide only input signals, only output signals, or both input/ output signals. For example, ESD testing group "VPP-VDD" indicates that ESD charges enter VPP and VDD pad is tied to 0 V.

IC failure criteria depend on two types of testing methodologies. The first method is I-V curve measurement. This method has voltage test at VPP from -12 V to +12 V combined with both terminals VDD and VSS in 0 V. VPP current (Ivpp) range is measured from  $-1.2~\mu A$  to  $1.2~\mu A$ . If VPP voltage shift is larger than 10% at Ivpp equal to  $+/-1~\mu A$ , IC is considered Fail; otherwise, IC is considered Pass. Fig. 12 illustrates the I-V curve measured by the machine Thermo Keytek Zapmaster. Pass testing result is illustrated in Fig. 12 (a) and Fail testing result in Fig. 12 (b). The second verification methodology depends on function testing (FT) result to check whether or not there are ESD currents entering OTP. If the OTP cell current reaches 1  $\mu A$ , IC is considered Fail; otherwise, IC is regarded as Pass.

Two kinds of ESD events, Human Body Model (HBM) and Machine Model (MM) are utilized in this study. Each ESD event has both kinds of stress polarities, positive and negative zapping. The stress voltages are





**Figure 12.** VPP to (VDD=VSS=0V) I-V curve. Failure criterion is voltage shift 10% at Ivpp =  $+/-1~\mu$ A. (a) There are no I-V curve shifts larger than 10% so IC passes I-V curve spec. (b) There are I-V curve shifts larger than 10% so IC fails I-V curve spec.

HBM +/- 2 kV and MM +/- 200 V, respectively. Table 1 illustrates HBM results verified by I-V curve shifts. Table 2 illustrates MM results verified by I-V curve shifts. Table 3 shows HBM results verified by FT results and Table 4 shows MM results verified by FT results.

Table 1 shows that all ESD circuits can pass HBM +/-2 kV. However, Table 3 reveals that only Circuit D can pass FT verifications. From Table 2, the curve testing results show that all circuits can pass MM +/-200 V, but FT results in Table 4 show that only Circuit D can pass MM +/-200 V. In other words, only Circuit D can approach the ESD target for protecting IC against HBM +/-2 kV and MM +/-200 V stresses. I-V curve

Table 1. HBM +/- 2 KV testing results based on I-V curve verifications.

Test item	Circuit A	Circuit B	Circuit C	Circuit D
VPP-VDD	Pass	Pass	Pass	Pass
VPP-VSS	Pass	Pass	Pass	Pass
VPP-IO	Pass	Pass	Pass	Pass

Table 2.  MM +/— 200 V testing results based on I-V curve verifications.					
Test item	Circuit A	Circuit B	Circuit C	Circuit D	
VPP-VDD VPP-VSS VPP-IO	Pass Pass Pass	Pass Pass Pass	Pass Pass Pass	Pass Pass Pass	

Table 3. HBM +/— 2 KV testing results based on IC function testing.					
Test item	Circuit A	Circuit B	Circuit C	Circuit D	
VPP-VDD VPP-VSS VPP-IO	3.3 μA 2.1 μA 2.5 μA	1.4 μA <1 μA 1.1 μA	2.3 μA 2.6 μA 2.3 μA	<1 μA <1 μA <1 μA	

Table 4.  MM +/- 200 V testing results based on IC function testing.				
Test item	Circuit A	Circuit B	Circuit C	Circuit D
VPP-VDD VPP-VSS VPP-IO	2.3 μA 8.8 μA 7.8 μA	3.2 μA 4.7 μA 9.7 μA	4.5 μA 7.8 μA 15.7 μA	<1 μA <1 μA <1 μA

verification methodology cannot detect OTP memory falsely programmed phenomenon, however. Thus, FT verification methodology is the correct method for deciding IC Pass/Fail ESD testing.

#### V. Falsely Programming Analysis

In order to discover ESD device behaviors, Transmission Line Pulse Generator (TLPG) [13–15] is applied to measure IC characteristics. There are two measuring modes in TLPG. One is TLPG mode for collecting device I-V data and the other is stand-by mode for measuring device stand-by currents. The waveform created by TLPG can be simplified as one square pulse on VPP in a 100ns period, as shown in Fig. 13.

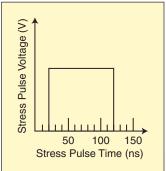
IC is considered Fail if VPP stand-by current reaches 10 nA because VPP normal stand-by current is below 2 nA@3.63 V (VPP voltage =3.63 V). This stand-by mode is only for IC current verifications, so the I-V curve is not shown here. The first breakdown voltage (Vt1) is ESD NMOS parasitic bipolar triggering-on voltage (snapback voltage) or VPP voltage when VPP current reaches 0.1 A in TLPG mode. The corresponding current is the first breakdown current (It1). Once the stand-by current reaches 10 nA, IC thermal run-away phenomenon occurs. The thermal run-away current is named secondary breakdown current (It2) and the thermal run-away voltage is named the secondary breakdown voltage

(Vt2) for distinguishing them from It1 and Vt1. Table 5 lists all Vt1, It1, Vt2 and It2 values. Fig. 14 illustrates TLPG I-V curve results for Circuits A-D at TLPG mode. From I-V curves, Circuits A and C that own GGNMOST as ESD protection circuit have ESD device snapback effects, but Circuits B and D that have GDNMOST as ESD protection circuit do not have such phenomena.

Since Vt1 (<2.5 V) of GDNMOST does not reach 7 V, VPP voltage does not necessarily reach the programming voltage when ESD device turns on. This result can reduce OTP memory

falsely programmed possibilities. It can also explain why GDNMOST is necessary for ESD protection circuit. However, TLPG voltage keeps on increasing after VPP reaches turn-on voltage. In Circuits B and D, VPP voltage reaches 7 V when VPP current is about 1.4 A. If VPP current is multiplied by 1.5 k $\Omega$  (HBM mode equal resistor), HBM endured voltages of IC are 2040 V and 2115 V for Circuit B and Circuit D, respectively. VPP voltage reaches 7 V under about 2000 V HBM stress, so ESD currents can enter OTP cells if there are no ESD avoiding circuits for preventing ESD currents from entering OTP cells. The above analysis explains why only Circuit D can pass HBM +/- 2 kV and MM +/- 200 V without any falsely programmed issues.

Usually, many circuit designers add a 100  $\Omega$  input resistor for preventing OTP memory from falsely programmed. The resistor cannot be designed to be too large; otherwise, OTP cells will encounter program efficiency issues. When ESD event happens, only a little ESD current can be allowed to enter OTP cells. For example, 1  $\mu A$  is the maximum current in this study. From the Ohm rule, there is only a maximum allowable voltage 0.1 mV (100  $\Omega$  \* 1  $\mu A$ ) on the input resistor at ESD events. Such small voltage dropping cannot stop ESD currents entering OTP cells, so the input resistor of Circuits B and C cannot avoid OTP cell to have falsely programmed issues.



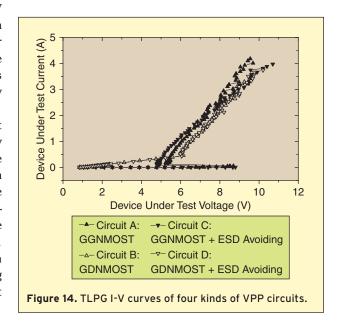
**Figure 13.** Ideal transmission line pulse generator (TLPG) square pulse in 100-ns period.

Briefly summarizing, for Circuits A-D, desired ESD dissipation path is the ESD current path 1, but ESD currents can flow the ESD current path 2 to falsely program OTP memory cells. OTP memory cells with Circuits A and B can be easily falsely programmed, whereas those memory cells with Circuits C and D are not because they have ESD avoiding circuit forming the ESD stopping wall. However, ESD devices of Circuit C cannot effectively turn on to dissipate ESD currents since Vt1 is too large. Finally, only Circuit D that owns ESD avoiding circuit and GDNMOST can

be chosen as ESD protection circuit for avoiding OTP memory cells falsely programmed.

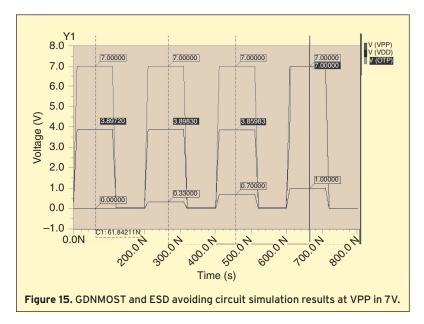
# VI. Simulation Analysis

Circuit D is the only circuit that has no OTP memory cell falsely programmed issues. In order to study the turning-on mechanism of Circuit D, TLPG 100 ns square



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TLPG testing results and OTP memory falsely programmed list. Circuit **ESD** protection lvpp (A) at lvpp (at 7V) imes 1.5  $\Omega$ **Falsely** name circuit Vt1(V) It1(A) Vt2(V) It2 (A) VPP=7 V k(V) programmed 0.056 4.5 Circuit A **GGNMOST** 8.8 9.5 4.18 0.003 Circuit B 2.2 2040 ٧ **GDNMOST** 0.1 9.6 3.45 1.36 Circuit C GGNMOST + ESD 3.97 3 8.9 0.006 10.7 0.002 avoiding GDNMOST + 2.3 0.101 3.94 2115 χ Circuit D 10.2 1.41 ESD avoiding



pulse shown in Fig. 13 is used to simulate Circuit D behaviors and H-spice is taken as the simulation tool. ESD event "VPP-VSS" is considered again. VPP tied to 7 V is considered as the simulation condition because OTP memory programmed voltage is 7 V. VPP is at 7 V and VSS is at 0 V, so floating terminal VDD coupled voltage is decided ideally by PMOS and NMOS size ratio through the inverter P3/N3, obeying the following equation:

VDD = VPP 
$$\times \frac{P3}{P3 + N3} = 7 \text{ V } \times \frac{2}{2 + 40} = 0.33 \text{ V.}$$
 (1)

The above description illustrates the ideal charge coupled result, but terminal VDD coupled voltage does not follow the above ideal equation. According to the charge coupled effect, VDD coupled voltage is considered having four kinds of values. The first condition is considering VDD coupled voltage as 0 V if terminal VDD is coupled to terminal VSS only; the second is VDD coupled voltage in 0.33 V from the ideal charge coupled equation; the third is VDD coupled voltage in 0.7 V if a little more charges are coupled to terminal VDD; the last condition is VDD coupled voltage in 1V if a lot of charges are coupled to terminal VDD.

The simulation program operates in four time divisions because of four kinds of VDD estimated voltages. Each time division has both rise time and fall time equal to 10 ns. From Fig. 15, one can see that if VDD coupled voltage is equal to 0 V, 0.33 V or 0.7 V, OTP memory voltage is about 3.9 V, much less than 7 V, so there are no falsely programmed events in OTP memories. However, if terminal VDD is coupled to 1V, OTP memories can reach 7 V and thus they can be falsely programmed. This is because the threshold voltage range of NMOS transistor is from 0.65 V to 0.95 V.

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There is no falsely programmed issue in Circuit D, so VDD coupled voltage is below 1 V under HBM +/- 2k V and MM +/- 200 V stresses in this study. Based on the above analyses, the coupled charge from terminal VPP to terminal VDD is very important under ESD stresses. P3 size must be kept as small as possible as compared to N3 size, so that P3 can turn on and then turn off transistor P4 under ESD stresses.

#### VII. Conclusions

Transmission gate N/PMOS transistors are the normal I/O circuits for signal controls, but no circuit designers use them for stopping ESD currents. In this study, since OTP memory cells are so sensitive to ESD currents, the

transmission N/PMOS transistors are adopted for preventing ESD currents from entering OTP memory cells. They are combined with one control inverter for forming the ESD avoiding circuit. Furthermore, in order to make ESD protection devices turn on at a smaller voltage, Gate-Driven circuit is used. If both Gate-Driven circuit and ESD avoiding circuit are adopted, there will be no OTP memory cell falsely programmed issues. Circuit designers can use the same technique to increase ICs' reliabilities. The transmission N/PMOS transistors controlled under the inverter not only stop ESD currents entering memories, but also work for preventing other unpredicted events from damaging IC, such as noise.

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